



Supplementary Materials: E" Raman Mode in Thermal Strain-Fractured CVD-MoS₂

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Figure S1. Typical setup of CVD system: (**a**) SiO₂ (300 nm)/p++Si substrate is face-down during the growth process of normal and OF- MoS₂; and (**b**) SiO₂ (300 nm)/p++Si substrate is face-up during the growth process of SF-MoS₂.



Figure S2. Close-up of the low-wavenumber region (100–270 cm⁻¹) where the first-order modes are located of SF-MoS₂. The red lines are the fitted Voigt peaks, and the black line is the experimental spectrum.



Figure S3. (a) Raman spectra excited by 488, 532 and 633 nm laser of SF-MoS₂ sample; and (b) Raman spectrum of SF-MoS₂ three months later.



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